



Development of the Electrochemical Solution Growth (ESG) Technique for Native GaN Substrates

DOE Energy Storage & Power Electronics Research Program 30 September 2008

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& Energy Storage Program







Outline

- Motivation
- Existing GaN Growth Technique
 - Epitaxial Lateral Overgrowth
 - Methods for Growing Bulk GaN
- Development of the Electrochemical Solution Growth Technique
 - Electroplating GaN from Ga⁺³ and N⁻³
 - Electrochemical Solution Growth (ESG)
 - Initial Results





Project Objective

To develop a novel, scalable, cost-effective growth technique for producing high quality, low dislocation density bulk gallium nitride for substrates for GaN-based power electronics.

Project Start: 5/08

Previous Funding: DOE's Solid-State Lighting

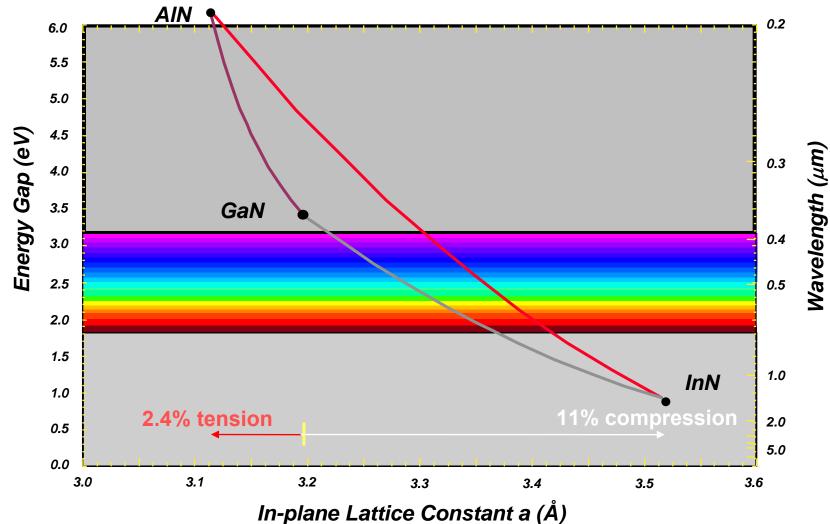




Combined Figure of Merit

	K (W/cm°C)	E _c (MV/cm)	3	μ (cm²/Vs)	Vs	Combined Figure of Merit
Si	1.31	0.3	11.8	1350	1 x 10 ⁷	1
SiC	4.9	2	10	650	2×10^7	136
GaN	1.3	3.3	9	1200	2.5×10^7	153

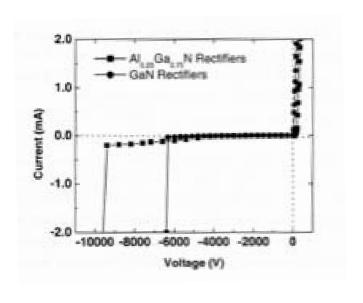
Energy gap - lattice parameter diagram of III-nitrides







Heterostructure Rectifiers Offer Improved Breakdown Voltages



9.7 kV for Al_{0.25}Ga_{0.75}N

Leakage current due to bulk defects



GaN is Grown Heteroepitaxially on Sapphire (and Silicon Carbide) Substrates

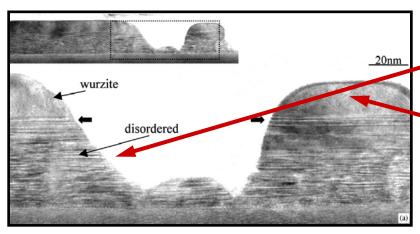
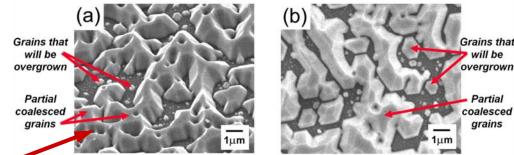


Figure from Lada et al., J. Crystal Growth 258, 89 (2003).

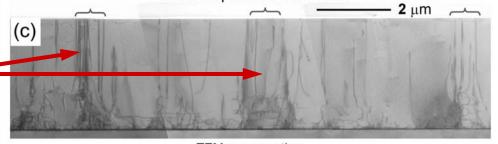
- High temperature growth on the GaN nuclei produces GaN grains.
- Growth conditions can be varied to enhance the <u>pyramidal growth mode</u> or lateral coalescence. Dislocations are bent laterally on pyramidal facets.
- Dislocations are concentrated in bunches located microns apart.

- As grown GaN nucleation layers contain disordered GaN with many stacking faults.
- Once annealed, wurtzite GaN forms on top of disordered GaN NL, forming nano-sized GaN nuclei from which further high temperature GaN growth occurs.

SEM Images of 3D GaN grain growth



The threading dislocation appear in bunches which are located a few microns apart from each other.



TEM cross section

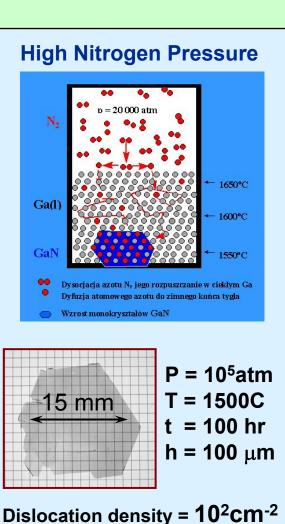
Methods for growing bulk GaN

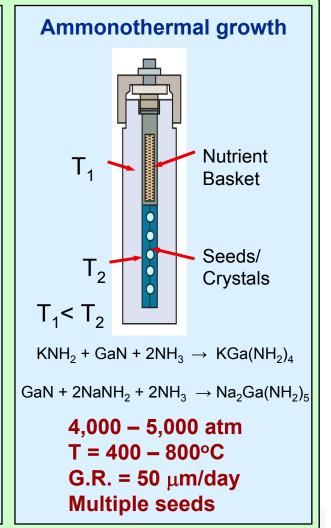
Dislocation Filtering Techniques Lateral Overgrowth HVPE GaN layer Sapphire Substrate Liftoff process

Polishing

Gall layer ?









Desires/Requirements for a Bulk Growth Technique

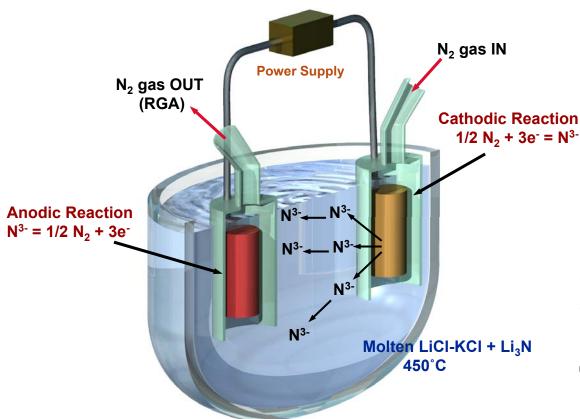
- Good crystalline quality ($\rho \le 1x10^5 \text{cm}^{-2}$)
- High growth rate (~mm/hr): high throughput, high volume production
- Low impurity content
- Scalable
- Controllable
- Manufacturable
- Reasonably inexpensive
- Applicable to InN, GaN, AIN, and III-N alloys



$1/2N_2 + 3e^{-} \rightarrow N^{-3}$: The Reactive Intermediate

T. Goto and Y. Ito, "Electrochemical reduction of nitrogen in a molten chloride salt" Electrochimica Acta, Vol. 43, Nos 21-22, pp 3379-3384 (1998).

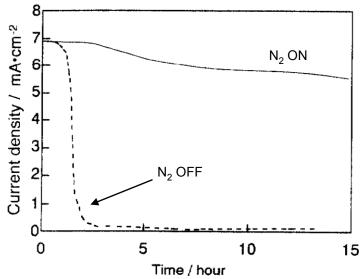
Found that nitrogen was continuously and nearly quantitatively reduced to nitride ions



Report of nitride concentration in LiCl in literature: 12 mole %

Advantages of using N2 gas:

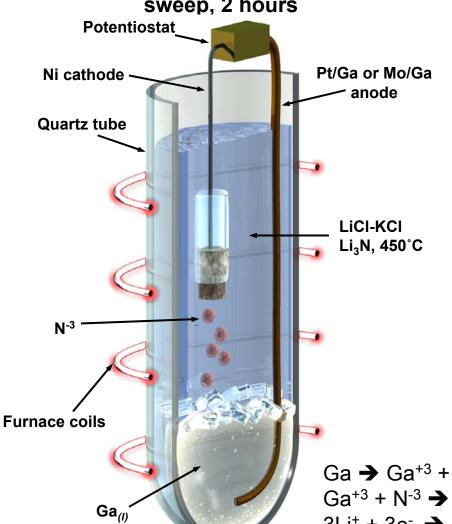
- Clean
- Inexpensive
- Control over precursor conc.
- Continuous, controlled supply

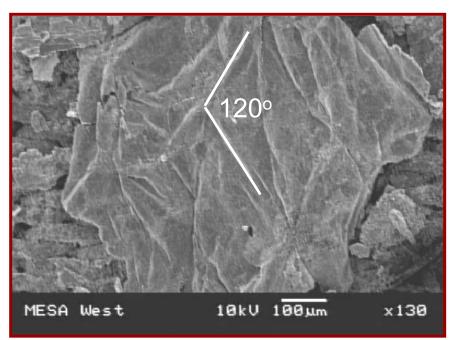




Initial Experimental Setup: Unseeded Growth of GaN in a Test Tube

 Li_3N or $(Li_3N + N_2) + Ga$, 450°C, current sweep, 2 hours



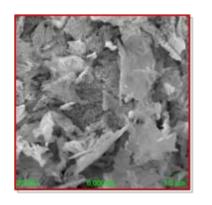


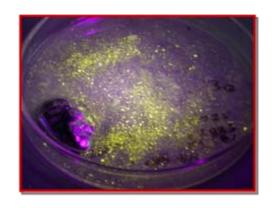
Produced numerous wurtzite GaN crystals; This crystal was ~1.25mm long x 0.8mm wide

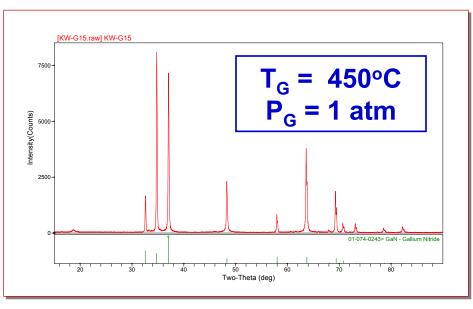
Ga
$$\rightarrow$$
 Ga⁺³ + 3e⁻
Ga⁺³ + N⁻³ \rightarrow GaN
3Li⁺ + 3e⁻ \rightarrow 3 Li

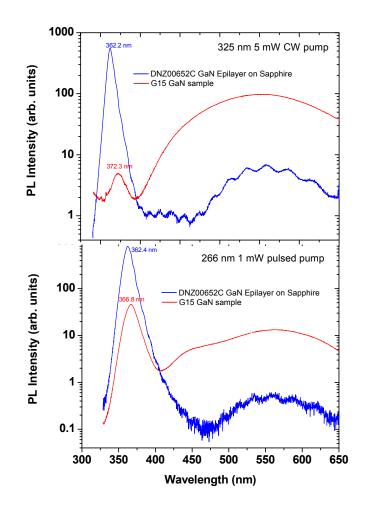


GaN ESG Produces Photoluminescent GaN Crystallites





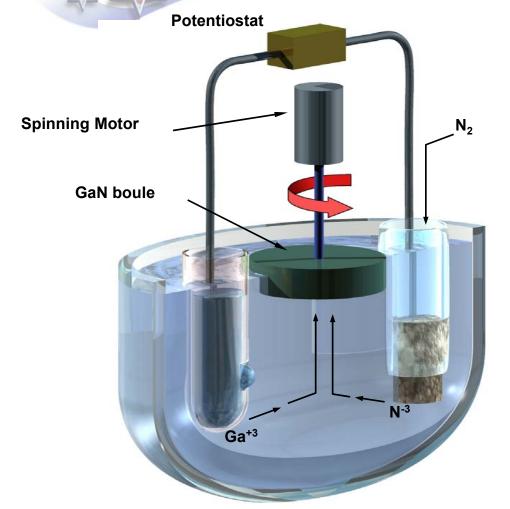




Mary Crawford, SNL



New Growth Technique: Electrochemical Solution Growth (ESG)



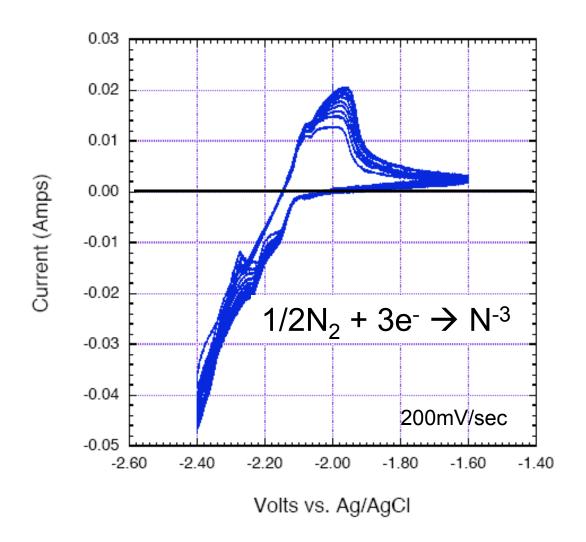
Use salt flow to deliver precursors Increase growth rate through flux of reactants (increase spin rate)

- Half-reaction 1:
 - $1/2N_2 + 3e^- \rightarrow N^{-3}$
 - N⁻³ concentrations ~12 mole %
- Half-reaction 2:
 - Ga \rightarrow Ga⁺³ + 3e⁻¹
 - Ga⁺³ equilibrium concentrations
 ~1 mole %

Precursors can be replenished as they are consumed Advantage: Continuous, isothermal or steady-state growth

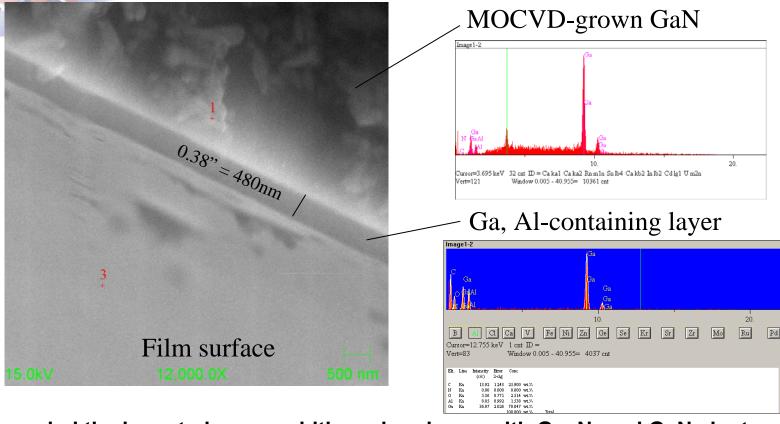


Example of Nitrogen Gas Reduction Cyclic Voltammograms





SEM of RD-ESG Growth Run #1



- SIMS revealed the layer to be a graphitic carbon layer, with Ga, N, and GaN clusters
 - GaN content was about 10%
 - Profile was consistent with an increasing concentration
- Problem with salt purity from supplier
 - Working it out with supplier
 - Developing in-house purification technique for reagent grade salt





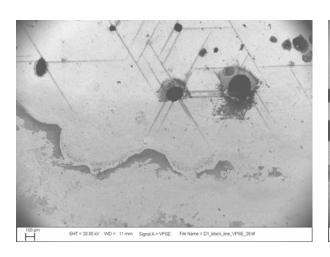
Industrial Partner (GNOEM) Hardware Development

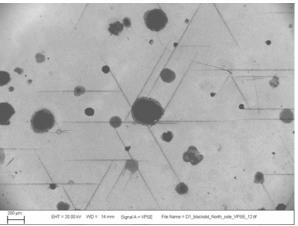


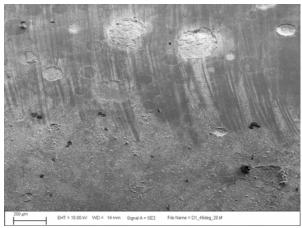




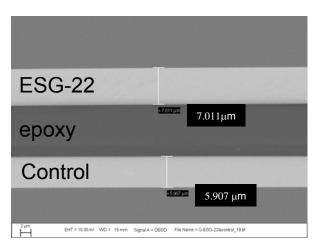
First GNOEM RD-ESG Experiment







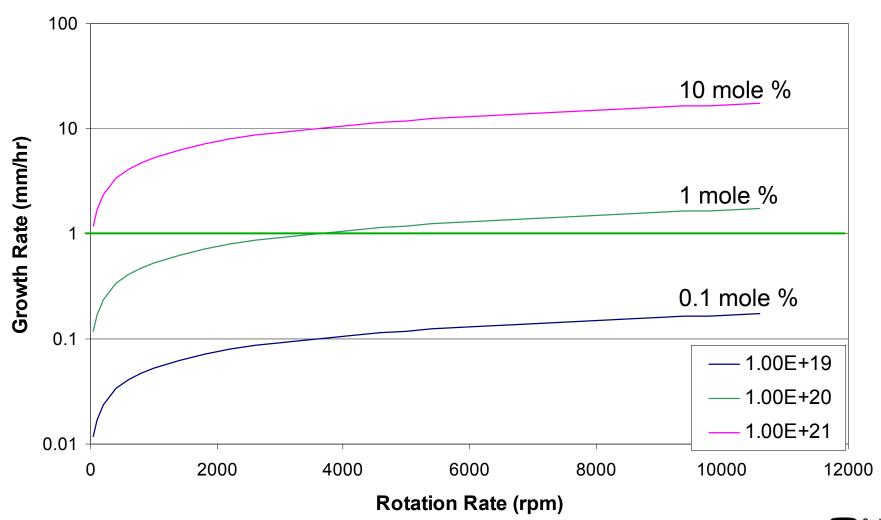
- Hardware failure
 – susceptor sheared, not sure when
- Black line on sample surface delineated a higher, specular region and lower, roughened area
- Defect selective etching observed (several microns/hr)
- Highly encouraging for crystal quality
 - Must identify the conditions under which this takes place
- Polished cross sections of control and experiment sample consistently measure about $1\mu m$ thicker for experiment







Growth Rate vs. Rotation Speed and Concentration







Summary: Path For Development

- Demonstrate that chemistry is viable
 - Kinetics and thermodynamics are favorable in this setup
- Check for dissolution and precipitation approach
- Develop N₂ electrochemical reduction methods
- Develop initial fluid dynamics schemes
- Deposit GaN on a seed crystal
 - Improve crystal quality
 - Optimize growth rate





Acknowledgments

- Jeff Tsao
- Tom Kerley
- Frank Delnick
- David Ingersoll
- Bill Averill
- Bob Biefeld
- Mike Coltrin
- Ryan Egidi
- National Energy Technology Laboratory/Energy Efficiency and Renewable Energy Office of Solid-State Lighting

- Paul Butler
- Tom Wunsch
- Dan Doughty
- Randy Creighton
- Christine White
- Dan Koleske
- Dave F. Smith
- George Antypas
- Mary Crawford
- Bertha Montoya

